

PATENT ASSIGNMENT COVER SHEET

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 Stylesheet Version v1.2

EPAS ID: PAT2819519

SUBMISSION TYPE:	NEW ASSIGNMENT
NATURE OF CONVEYANCE:	ASSIGNMENT
CONVEYING PARTY DATA	
Name	Execution Date
REPLISAURUS TECHNOLOGIES AB	11/04/2010
REPLISAURUS TECHNOLOGIES INC	11/04/2010
RECEIVING PARTY DATA	
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State/Country:	FRANCE
Postal Code:	69410
PROPERTY NUMBERS Total: 1	
Property Type	Number
Application Number:	14135745
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NAME OF SUBMITTER:	JAMES E. WALTON
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DATE SIGNED:	04/17/2014
Total Attachments: 4	
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ASSIGNMENT

On this day, the 4th of November 2010,

It is hereby declared that we have assigned to:

REPLISAURUS GROUP SAS
Le Soleil Levant, Immeuble Sendaï 11, chemin des
Anciennes Vignes
69410 Champagne au Mont d'Or,
France

Our entire rights in and to all patent applications and patents - as per enclosure 1 - now
registered with

REPLISAURUS TECHNOLOGIES AB
Isafjordsgatan 22 B, 5v
SE-164 40 KISTA
Sweden

and

REPLISAURUS TECHNOLOGIES INC
1209 Orange Street
WILMINGTON, DE 19801
USA

as applicants.

4-11-2010
.....
Place and date

REPLISAURUS TECHNOLOGIES AB


.....
Signature of Assignor

DANIEL A. CARL
.....
Name in block letters

4-11-2010
REPLISAURUS TECHNOLOGIES INC


.....
Signature of Assignor

DANIEL A. CARL
.....
Name in block letters

The above assignment is accepted.

REPLISAURUS GROUP SAS

Place and date: 4/11/2010
.....


.....
Signature of Assignee

GUSTAV JAKOB
.....
Name in block letters

It is hereby certified that this is a
true and correct copy of the
document:



ENCLOSURE 1

Patent applications as per November 4, 2010

Ref. no.	State	Application no.	Pat./Reg.nr	Title	Applicant
P52190001	Sweden	0102144-3	523 309	METHOD FOR DEFINING AND REPLICATING STRUCTURE IN CONDUCTING MATERIAL	REPLISAURUS TECHNOLOGIES AB
ES2190001	E P O	02739042.6		METHOD FOR DEFINING AND REPLICATING STRUCTURE IN CONDUCTING MATERIAL	REPLISAURUS TECHNOLOGIES AB
ES2191001	E P O	10182946.3		METHOD FOR DEFINING AND REPLICATING STRUCTURE IN CONDUCTING MATERIAL	REPLISAURUS TECHNOLOGIES AB
P52190001CA	Canada	2,462,098		METHOD FOR DEFINING AND REPLICATING STRUCTURE IN CONDUCTING MATERIAL	REPLISAURUS TECHNOLOGIES AB
P52190001CN	China	02811926.6	ZL02811926.6	METHOD FOR DEFINING AND REPLICATING STRUCTURE IN CONDUCTING MATERIAL	REPLISAURUS TECHNOLOGIES AB
P52190001HK	Hong Kong	05104929.3	HK1072083	METHOD FOR DEFINING AND REPLICATING STRUCTURE IN CONDUCTING MATERIAL	REPLISAURUS TECHNOLOGIES AB
P52190001IN	India	02129/DELNP/2003		METHOD FOR DEFINING AND REPLICATING STRUCTURE IN CONDUCTING MATERIAL	REPLISAURUS TECHNOLOGIES AB
P52190001JP	Japan	2003-505393	4546078	METHOD FOR DEFINING AND REPLICATING STRUCTURE IN CONDUCTING MATERIAL	REPLISAURUS TECHNOLOGIES AB
P52191001JP	Japan	2009-142804		METHOD FOR DEFINING AND REPLICATING STRUCTURE IN CONDUCTING MATERIAL	REPLISAURUS TECHNOLOGIES AB
P52190001KR	South Korea	2003-7016336		METHOD FOR DEFINING AND REPLICATING STRUCTURE IN CONDUCTING MATERIAL	REPLISAURUS TECHNOLOGIES AB
P52190001MY	Malaysia	P1 20034732		METHOD FOR DEFINING AND REPLICATING STRUCTURE IN CONDUCTING MATERIAL	REPLISAURUS TECHNOLOGIES AB
P52190001PH	Philippines	1-2003-501274	1-2003-501274	METHOD FOR DEFINING AND REPLICATING STRUCTURE IN CONDUCTING MATERIAL	REPLISAURUS TECHNOLOGIES AB
P52190001RU	Russia	2003136088	2296820	METHOD FOR DEFINING AND REPLICATING STRUCTURE IN CONDUCTING MATERIAL	REPLISAURUS TECHNOLOGIES AB
P52190001SG	Singapore	200307357-4	101 252	METHOD FOR DEFINING AND REPLICATING STRUCTURE IN CONDUCTING MATERIAL	REPLISAURUS TECHNOLOGIES AB
P52190001US	USA	10/734 223		METHOD FOR DEFINING AND REPLICATING STRUCTURE IN CONDUCTING MATERIAL	REPLISAURUS TECHNOLOGIES AB
P52192001US	USA	12/801 219		METHOD FOR DEFINING AND REPLICATING STRUCTURE IN CONDUCTING MATERIAL	REPLISAURUS TECHNOLOGIES AB
ES2190002	E P O	06813033.5		METHOD OF FORMING A MULTILAYER STRUCTURE	REPLISAURUS TECHNOLOGIES AB
P52190002CN	China	200680051024.3		METHOD OF FORMING A MULTILAYER STRUCTURE	REPLISAURUS TECHNOLOGIES AB
P52190002JP	Japan	2008-541118		METHOD OF FORMING A MULTILAYER STRUCTURE	REPLISAURUS TECHNOLOGIES AB
P52190002KR	South Korea	2008-7014730		METHOD OF FORMING A MULTILAYER STRUCTURE	REPLISAURUS TECHNOLOGIES AB
P52190002US	USA	12/085 176		METHOD OF FORMING A MULTILAYER STRUCTURE	REPLISAURUS TECHNOLOGIES AB
P52191002US	USA	12/412 319		METHOD OF FORMING A MULTILAYER STRUCTURE	REPLISAURUS TECHNOLOGIES AB
P52192002US	USA	12/412 322		METHOD OF FORMING A MULTILAYER STRUCTURE	REPLISAURUS TECHNOLOGIES AB

NA

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Patent applications as per November 4, 2010

ES2190003	E P O	06824464.9	ELECTRODE AND METHOD OF FORMING THE ELECTRODE	REPUSAURUS TECHNOLOGIES AB
PS2190003CN	China	200680051145.8	MASTER ELECTRODE AND METHOD OF FORMING THE MASTER ELECTRODE	REPUSAURUS TECHNOLOGIES AB
PS2190003JP	Japan	2008-541119	MASTER ELECTRODE AND METHOD OF FORMING THE MASTER ELECTRODE	REPUSAURUS TECHNOLOGIES AB
PS2190003KR	Sydkorea	2008-7014733	MASTER ELECTRODE AND METHOD OF FORMING THE MASTER ELECTRODE	REPUSAURUS TECHNOLOGIES AB
PS2190003US	USA	12/085 157	MASTER ELECTRODE AND METHOD OF FORMING THE MASTER ELECTRODE	REPUSAURUS TECHNOLOGIES AB
PS2191003US	USA	12/470 448	MASTER ELECTRODE AND METHOD OF FORMING THE MASTER ELECTRODE	REPUSAURUS TECHNOLOGIES AB
PS2192003US	USA	12/470 452	MASTER ELECTRODE AND METHOD OF FORMING THE MASTER ELECTRODE	REPUSAURUS TECHNOLOGIES AB
PS2193003US	USA	12/470 444	MASTER ELECTRODE AND METHOD OF FORMING THE MASTER ELECTRODE	REPUSAURUS TECHNOLOGIES AB
ES2190005	E P O	06813034.3	MASTER ELECTRODE AND METHOD OF FORMING IT	REPUSAURUS TECHNOLOGIES AB
PS2190005CN	China	200680051055.9	MASTER ELECTRODE AND METHOD OF FORMING IT	REPUSAURUS TECHNOLOGIES AB
PS2190005JP	Japan	2008-541120	MASTER ELECTRODE AND METHOD OF FORMING IT	REPUSAURUS TECHNOLOGIES AB
PS2190005KR	South Korea	2008-7014735	MASTER ELECTRODE AND METHOD OF FORMING IT	REPUSAURUS TECHNOLOGIES AB
PS2190005US	USA	12/094 142	MASTER ELECTRODE AND METHOD OF FORMING IT	REPUSAURUS TECHNOLOGIES AB
WS2190006	P C T	PCT/EP2008/009658	A SYSTEM FOR PLATING A CONDUCTIVE SUBSTRATE, AND A SUBSTRATE HOLDER FOR HOLDING REPUSAURUS TECHNOLOGIES INC	
PS2190006TW	Taiwan	98131796	A SYSTEM FOR PLATING A CONDUCTIVE SUBSTRATE, AND A SUBSTRATE HOLDER FOR HOLDING REPUSAURUS TECHNOLOGIES INC	
PS2190007	Sweden	1050795-2	SYSTEM FOR AUTOMATED HANDLING OF MASTERS AND SUBSTRATE	REPUSAURUS TECHNOLOGIES AB
PS2190007US	USA	61/364 989	NEW MATTER	REPUSAURUS TECHNOLOGIES AB
PS2190008	Sweden	1050796-0	A CHUCK AND A METHOD FOR BRINGING A FIRST AND A SECOND SUBSTRATE TOGETHER	REPUSAURUS TECHNOLOGIES AB
PS2190009	Sweden	1050797-8	CONTACT BRINGING MEANS FOR AN ECPR MASTER ELECTRODE AND A SUBSTRATE TOGETHER REPUSAURUS TECHNOLOGIES AB	
PS2190010	Sweden	1050798-6	SEPARATION OF MASTER ELECTRODE AND SUBSTRATE IN ECPR	REPUSAURUS TECHNOLOGIES AB
PS2190011	Sweden	1050799-4	LEVELING OF MASTER ELECTRODE AND SUBSTRATE IN ECPR, AND A CHUCK THEREFORE	REPUSAURUS TECHNOLOGIES AB

ENCLOSURE 1

Patent applications as per November 4, 2010

P52190012	Sweden	1050800-0	FILING OF A PRINTING CHAMBER AND A CHUCK THEREFORE	REPUSAURUS TECHNOLOGIES AB
P52190013	Sweden	1050801-8	RINSING/DRYING - METHOD FOR RINSING AND/OR DRYING AN ECPR CHAMBER, AND CHUCKS REPUSAURUS TECHNOLOGIES AB	
P52190014	Sweden	1050802-6	DEVICE, SYSTEM AND METHOD FOR USE IN MACHINES FOR ELECTROCHEMICAL PATTERN REP REPUSAURUS TECHNOLOGIES AB	
P52190015	Sweden	1050803-4	METHOD AND SYSTEM FOR DETECTING, SETTING AND MONITORING THE SPATIAL SITUATION REPUSAURUS TECHNOLOGIES AB	

It is hereby certified that this is a true and correct copy of the original document:

Ulf-Dieter Dybbel